

Form PTO-1449

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICEATTY. DOCKET NO.
MI22-1724SERIAL NO.
UnknownLIST OF ART CITED BY APPLICANT
(Use several sheets if necessary)APPLICANT
Cem Basceri et al.FILING DATE
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Unknown

U.S. PATENT DOCUMENTS

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
EF	AA			Cem Basceri et al. (as filed)			Filed Concurrently
EF	AB	09/476,516		Cem Basceri (as filed and as amended)			01/03/00
EF	AC	09/580,733		Cem Basceri (as filed)			05/26/00
EF	AD	5,459,635	10/17/95	Tomozawa et al.	361	321.5	
EF	AE	5,618,761	04/08/97	Eguchi et al.	438	785	
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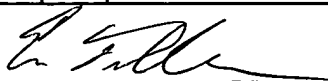
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12/06/01

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09/905,286

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APPLICANT
Cem Basceri et al.

FILING DATE
July 13, 2001

GROUP
Unknown

U.S. PATENT DOCUMENTS

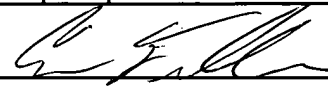
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EF	AA	5,256,455	10/26/93	Numasawa			
EF	AB	5,731,948	01/21/97	Endo			
EF	AC	5,776,254	03/24/98	Yializis et al.			
EF	AD	5,783,253	07/07/98	Yuuki et al.			
EF	AE	5,798,903	07/21/98	Roh			
EF	AF	6,043,526	08/25/98	Dhote et al.			
EF	AG	6,046,345	03/28/00	Ochiai			
EF	AH	6,078,492	04/04/00	Kadokura et al.			
EF	AI	6,153,898	06/20/00	Huang et al.			
EF	AJ	6,037,205	11/28/00	Watanabe			
EF	AK	6,037,205	03/14/00	Huh et al.			

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
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EF	AL	0 855 735 A2	26.01.98	EPO - Zhao et al.; Applied Materials, Inc.				
EF	AM	0 957 522 A2	12.05.99	EPO - Ueda, Michihito; Matsushita Electric Ind. Co.,				
EF	AN	WO 98/39497	20.02.98	WIPO - Simpson, John et al.				
EF	AO	0 474 140 A1	30.08.91	EPO - Kamiyama, Satoshi c/o NEC Corporation				
EF	AP	WO 99/64645	11.06.99	WIPO - Narwankar et al.; Applied Materials, Inc;				

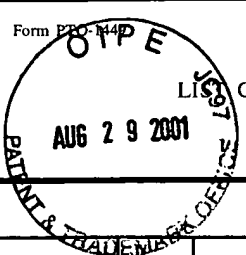
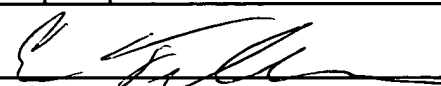
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

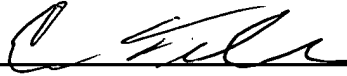
EF	AR	Steve Bilodeau et al., <i>Composition Dependence of the Dielectric Properties of MOCVD Ba_{0.5}Sr_{0.5}TiO₃</i> , pp. 1-21 (MRS Fall Meeting 12/01/94).
EF	AS	Steve M. Bilodeau et al., <i>MOCVD BST for High Density DRAM Applications</i> (Preprint for SEMICON/WEST 07/12/95), 2 pages.
EF	AT	Y-C Choi et al., Abstract, <i>Improvements of the Properties of Chemical-Vapor-Deposited (Ba,Sr)TiO₃ Films Through Use of a Seed Layer</i> , 36 JPN. J. APPL. PHYS. Pt. 1, No. 11, pp. 6824-6828 (1997)

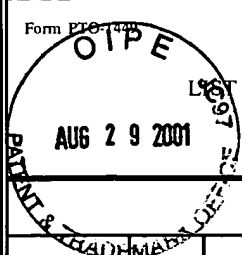

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Form PTO-1449 <div style="text-align: center;">  </div>		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M122-1724		SERIAL NO. 09/905,286	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Cem Basceri et al.		GROUP Unknown	
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U.S. PATENT DOCUMENTS							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
EF	AA	5/470,398	11/28/95 Shibuya et al.				
EF	AB	5/254,505	10/19/93 Kaniyama				
EF	AC	6,156,638	12/05/00 Agarwal et al.				
EF	AD	6,165,834	12/26/00 Agarwal et al.				
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OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
EF	AR	Chung Ming Chu et al., Abstract, <i>Electrical properties and crystal structure of (Ba,Sr)TiO₃ films prepared at low temperatures</i>					
		on a LaNiO ₃ electrode by radio-frequency magnetron sputtering, 70 APPLIED PHYSICS LETTERS No. 2, pp. 249-251 (1997).					
EF	AS	Kazuhiro Eguchi et al., Abstract, <i>Chemical vapor deposition of (Ba,Sr)TiO₃ thin films for application in gigabit scale</i>					
		dynamic random access memories, 14 INTEGRATED FERROELECTRICS Nos. 1-4, Pt. 1, pp. 33-42 (1997).					
EF	AT	Q.X. Jia et al., Abstract, <i>Structural and dielectric properties of Ba_{0.5}Sr_{0.5} thin films with an epi-RuO₂ bottom electrode,</i>					
		19 INTEGRATED FERROELECTRICS Nos. 1-4, pp. 111-119 (1998).					
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	AM				
	AN				
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	AP				
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EF	AR	Takaaki Kawahara et al., (Ba, Sr)TiO ₃ Films Prepared by Liquid Source Chemical Vapor Deposition on Ru Electrodes, 35 JPN. J. APPL. PHYS. Pt. 1, No. 9B, pp. 4880, 4883 (1996).			
EF	AS	Rajesh Khamankar et al., A Novel Low-Temperature Process for High Dielectric Constant BST Thin Films for ULSI DRAM Applications, Microelectronics Research Center, Univ. of Texas at Austin, TX (Undated), 2 pages.			
EF	AT	Yong Tae Kim et al., Abstract, Advantages of RuO ₄ bottom electrode in the dielectric and leakage characteristics of (Ba,Sr)TiO ₃ capacitor, 35 JPN. J. APPL. PHYS. Pt. 1, No. 12A, pp. 6153-6156 (1996).			
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EF	AR		S.H. Paek et al., Abstract, <i>Characterization of MIS capacitor of BST thin films deposited on Si by RF magnetron sputtering.</i>					
			Ferroelectric Thin Films V. Symposium, San Francisco, CA, pp. 33-38 (April 7, 1995).					
EF	AS		N. Takeuchi et al., Abstract, <i>Effect of firing atmosphere on the cubic-hexagonal transition in Ba_{0.99}Sr_{0.01}TiO₃</i> , 98 NIPPON					
			SERAMIKKUSU KYOKAI GAKUJUTSU RONBUNSHI No. 8, pp. 836-839 (1990).					
EF	AT		H. Yamaguchi, et al., Abstract, <i>Reactive coevaporation synthesis and characterization of SrTiO₃-BaTiO₃ thin films</i> , IEEE					
			International Symposium on Applications of Ferroelectrics, Greenville, SC, pp. 285-288 (August 2, 1992).					
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EF	AR		S. Yamamichi et al., Abstract, <i>Ba + Sr/Ti ratio dependence of the dielectric properties for (Ba_{0.5})Sr_{0.5}TiO₃ thin films prepared by ion beam sputtering</i> , 64 APPLIED PHYSICS LETTERS No. 13, pp. 1644-1646 (1994).					
EF	AS		M. Yamamuka et al., Abstract, <i>Thermal-Desorption Spectroscopy of (Ba,Sr)TiO₃ Thin-Films Prepared by Chemical-Vapor-Deposition</i> , 35 JPN. J. OF APPL. PHYS. Pt. 1, No. 2A, pp. 729-735 (1996).					
EF	AT		Arai T., et al.: <i>Preparation of SrTiO₃ Films on 8-Inch Wafers by Chemical Vapor Deposition</i> , Jap. Journal of Applied Physics, Vol. 35, No. 9B, Part 01, 09/01/96, Pgs. 4875-4879					
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EF	AR		Kim, et al.: <i>Structural and Electrical Properties of BaTiO₃ grown on p-InP (100) by low-pressure metalorganic chemical vapor deposition at low temperature</i> , Applied Physics Letters, US, American Institute of Physics Vol. 65, No. 15, 10/10/94, Pgs. 1955-1957.				
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